

List of reference symbols

M	Marking
M ₁ -M ₃	Structure of the marking
W	Wafer
C	Chuck
S _I	Intensity profile of the marking
S _A	Line profile of the marking
X, Y	Scanning direction
Δx, Δy	Offset
x ₁ , y ₁	First position information items
x ₂ , y ₂	Second position information items
x _I , y _I	Edge position from intensity profile
x _A , y _A	Edge position from line profile
10	Alignment system
11	Mount
20	First optical measuring device
21	Alignment microscope
22	Light source
23	Light radiation from the light source 22
30	Scattered radiation measuring device
31	Detector for scattered light radiation
32	Light source for scattered radiation measurement
33	Light radiation from the light source 32
40	Data processing device
41	Comparison device
42	Database
50	Positioning device
60	Lithography installation
61	Exposure unit